

Docket No.: 060188-0658

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Application of

Masashi HAMANAKA, et al.

Application No.: 10/671,502

Filed: September 29, 2003

: Customer Number: 20277

: Confirmation Number: 8488

: Group Art Unit: 3723

: Examiner: RACHUBA, MAURINA T

For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

PETITION FOR EXTENSION OF TIME

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

It is respectfully requested that the time for response to the Office Action dated January 27, 2006, now due to expire April 27, 2006, be extended for one month and set to expire on May 30, 2006, (as May 27, 2006 falls on a Saturday and Monday, May 29 is a Federal Holiday).

Please charge the extension fee of \$120.00 to Deposit Account No. 500417. Please charge any additional fees or credit any overpayment to Deposit Account No. 500417.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP

Michael E. Fogarty
Registration No. 36,139

**Please recognize our Customer No. 20277
as our correspondence address.**

06/01/2006 HALI11 00000013 500417 10671502
02 FC:1251 120.00 DA

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Date: May 30, 2006